ADVANCE INFORMATION



DLP2021-Q1 0.2 英寸 16:9 数字微镜器件

1 特性

- 具有符合 AEC-Q100 标准的下列特性:
 - 器件温度等级 2:-40°C 至 +105°C 环境工作温
 - 人体放电模型 (HBM) ESD 分类等级 1C
 - 充电器件模型 (CDM) ESD 分类等级 C4B
- 0.2 英寸对角线微镜阵列
 - 7.6µm 微镜间距
 - ±12° 微镜倾斜角(相对于平面)
 - 可减小系统尺寸的侧向照明
- 16:9 (588 × 330) 输入分辨率
- 高达 832 × 468 的有效分辨率
- 偏振无关型空间光调制器
- 与 LED 或激光光源兼容
- 低功耗: 260mW(最大值)
- 工作温度范围: 40°C 至 105°C
- 气密封装
- 80MHz 双倍数据速率 (DDR) 数字微镜器件 (DMD) 接口

2 应用

- 动态地面投影
- 车辆内外视频投影

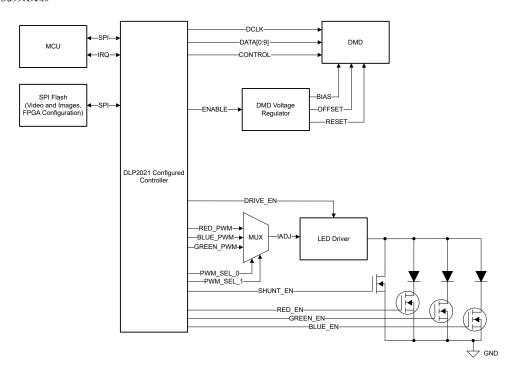
3 说明

DLP2021-Q1 汽车数字微镜器件 (DMD) 专为汽车外部 照明控制和显示应用而设计。应用包括显示全彩色和动 画及动态内容的地面投影。地面投影有助于实现车辆对 行人 (V2P) 通信,例如倒车和车门打开警告,以及协 调车辆通信系统和汽车个性化选项。由于尺寸小且运行 功耗低,采用 DLP2021-Q1 芯片组的投影仪可以支持 很多投影应用。这类投影仪可以安装在车辆上的很多位 置,例如后视镜、车门、尾灯以及前格栅等等。

器件信息

| 器件型号(1) | 封装 | 封装尺寸 (标称值) |
|------------|----------|------------------|
| DLP2021-Q1 | FQU (64) | 8.55mm × 16.80mm |

如需了解所有可用封装,请参阅数据表末尾的可订购产品附 录。



DLP2021-Q1 系统方框图



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4 Revision History 注:以前版本的页码可能与当前版本的页码不同

| С | Changes from Revision * (February 2022) to Revision A (November 2022) | Page |
|---|---|------|
| • | 根据最新的德州仪器 (TI) 和行业数据表标准对本文档进行了更新 | 1 |
| • | Updated Electrostatic discharge HBM value | 5 |
| • | Updated RESET STROBE Setup and Hold values | 8 |

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5 说明(续)

该芯片组能够与 LED 或激光器搭配使用,以生成具有 125% 以上国家电视系统委员会 (NTSC) 色域的高饱和度颜色,并且可以与 RGB 或白色光源搭配使用。DLP2021-Q1 具有现场可编程门阵列 (FPGA) 配置,可用于驱动 DLP2021-Q1 汽车 DMD。此控制器架构专为小型投影仪而设计,不需要视频总线或图形处理单元 (GPU) 即可创建内容。视频和图像内容存储在本地闪存中,上电即可播放,也可根据命令进行播放。

6 Pin Configuration and Functions

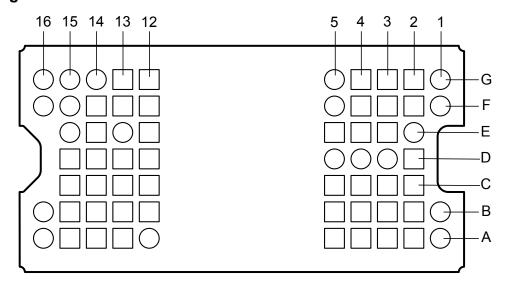


图 6-1. FQU Package 64-Pin LGA Bottom View



Pin Functions

| Pin Functions | | | | | | |
|---|--|----------------|--|--|--|--|
| PIN | | TYPE | DESCRIPTION | | | |
| NAME | NO. | 111.5 | DECORII TION | | | |
| DATA(0) | A2 | | | | | |
| DATA(1) | A4 | | | | | |
| DATA(2) | B2 | | | | | |
| DATA(3) |) B3 | | | | | |
| DATA(4) | B5 | | Data bus. Synchronous to riging edge and falling edge of DCLK | | | |
| DATA(5) | C2 | | Data bus. Synchronous to rising edge and falling edge of DCLK | | | |
| DATA(6) | C3 | | | | | |
| DATA(7) | B4 | | | | | |
| DATA(8) | C5 | | | | | |
| DATA(8) C5 DATA(9) D2 DCLK F4 | | | | | | |
| DCLK | F4 | | Data clock | | | |
| LOADB | F3 | LVCMOS input | Parallel latch load enable. Synchronous to rising edge and falling edge of DCLK | | | |
| SCTRL | E4 | | Serial control (sync). Synchronous to rising edge and falling edge of DCLK | | | |
| TRC | F2 | | Toggle rate control. Synchronous to rising edge and falling edge of DCLK | | | |
| DAD_BUS | B15 | | Reset control serial bus. Synchronous to rising edge of SAC_CLK | | | |
| RESET_OEZ | C15 | | Active low. Output enable signal for internal reset driver circuitry | | | |
| RESET_STROBE | B13 | | Rising edge on RESET_STROBE latches in the control signals | | | |
| SAC_BUS | A15 | | Stepped address control serial bus. Synchronous to rising edge of SAC_CLK | | | |
| SAC_CLK | A14 | | Stepped address control clock | | | |
| TEMP_MINUS | G13 | Analog input | Calibrated temperature diode used to assist accurate | | | |
| TEMP_PLUS | G2 | Arialog Iriput | temperature measurements of DMD die | | | |
| V _{BIAS} | D15 | | Power supply for positive bias level of mirror reset signal | | | |
| Vcc | A5, B12, C14, D12, F13, G3 | | Power supply for low voltage CMOS logic. Power supply for normal high voltage at mirror address electrodes. Power supply for offset level of mirror reset signal during power down | | | |
| V _{OFFSET} | E14 | Power | Power supply for high voltage CMOS logic. Power supply for stepped high voltage at mirror address electrodes. Power supply for offset level of mirror reset signal | | | |
| V _{RESET} | D14 | | Power supply for negative reset level of mirror reset signal | | | |
| V _{SS} | A3, A13, B14, C4, C12, C13, D13, E3, E5, E12, F12, F14, G4, G12 | | Common return for all power | | | |
| RESERVED | A1, A12, A16,B1, B16, D3, D4, D5, E2, E13,E15, F1, F5, F15, F16, G1, G5, G14, G15, G16 | Reserved | Do not connect. | | | |

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7 Specifications

7.1 Absolute Maximum Ratings

See (1)

| | | MIN | NOM MAX | UNIT |
|---|--|-------|-----------------------|--------|
| SUPPLY VOLTAGE | | | | ı |
| V_{DD} | LVCMOS logic supply voltage | - 0.5 | 2.3 | V |
| V _{OFFSET} | Supply voltage for HVCMOS and micromirror electrode | - 0.5 | 8.75 | V |
| V _{BIAS} | Supply voltage for micromirror electrode | - 0.5 | 17 | V |
| V _{RESET} | Supply voltage for micromirror electrode | - 11 | 0.5 | V |
| V _{BIAS} - V _{OFFSET} | Supply voltage delta (absolute value) | | 8.75 | V |
| V _{BIAS} - V _{RESET} | Supply voltage delta (absolute value) | | 28 | V |
| INPUT VOLTAGE | | | | |
| Input voltage for LVC | MOS Pins | - 0.5 | V _{DD} + 0.5 | V |
| TEMPERATURE DIC | DE | | | |
| I _{TEMP_DIODE} | Max current source into temperature diode | | 500 | μA |
| ENVIRONMENTAL | | - | | |
| T _{ARRAY} | Operating DMD array temperature | - 40 | 105 | °C |
| ILL _{OVERFILL} | Illumination overfill maximum heat load in area shown in Illumination Overfill Diagram | | 50 | mW/mm² |

⁽¹⁾ Operation outside the Absolute Maximum Ratings may cause permanent device damage. Absolute Maximum Ratings do not imply functional operation of the device at these or any other conditions beyond those listed under Recommended Operating Conditions. If outside the Recommended Operating Conditions but within the Absolute Maximum Ratings, the device may not be fully functional, and this may affect device reliability, functionality, performance, and shorten the device lifetime.

7.2 Storage Conditions

Applicable for the DMD as a component or non-operating in a system.

| | | MIN | MAX | UNIT |
|------------------|-------------------------|------|-----|------|
| T _{stg} | DMD storage temperature | - 40 | 125 | °C |

7.3 ESD Ratings

| | | | VALUE | | UNIT |
|-------------------|---------------------------|------------------------------------|-------------------------|-------|------|
| V | Electrostatic discharge | Human body model (HBM), per AEC | Q100-002 ⁽¹⁾ | ±1000 | V |
| V _{(ESD} |) Electrostatic discharge | Charged device model (CDM), per Al | EC Q100-011 | ±750 | V |

⁽¹⁾ AEC Q100-002 indicates that HBM stressing shall be in accordance with the ANSI/ESDA/JEDEC JS-001 specification.

7.4 Recommended Operating Conditions

Over operating free-air temperature range (unless otherwise noted)(1)

| | | MIN | NOM | MAX | UNIT |
|---|--|-------|------|--------|------|
| SUPPLY VOLTAGE | RANGE | | | | |
| V_{DD} | Supply voltage for LVCMOS core logic Supply voltage for LPSDR low-speed interface | 1.7 | 1.8 | 1.95 | V |
| V _{OFFSET} | Supply voltage for HVCMOS and micromirror electrode | 8.25 | 8.5 | 8.75 | V |
| V _{BIAS} | Supply voltage for mirror electrode | 15.5 | 16 | 16.5 | V |
| V _{RESET} | Supply voltage for micromirror electrode | - 9.5 | - 10 | - 10.5 | V |
| V _{BIAS} - V _{OFFSET} | Supply voltage delta (absolute value) | | | 8.75 | V |
| V _{BIAS} - V _{FRESET} | Supply voltage delta (absolute value) | | | 28 | V |
| LVCMOS Buffers | ' | - | | | |



7.4 Recommended Operating Conditions (continued)

Over operating free-air temperature range (unless otherwise noted)(1)

| | | MIN | NOM | MAX | UNIT |
|-------------------------|--|------|------|-------|--------------------|
| V _{IH} | Positive going threshold voltage | 0.7 | VDD | 0+0.3 | x V _{DD} |
| V _{IL} | Negative going threshold voltage | -0.3 | | 0.3 | x V _{DD} |
| CLOCK FREQUE | ENCY | | | | |
| $f_{\sf max}$ | Clock frequency for high speed interface SAC_CLK | 20 | 76.2 | 80 | MHz |
| DCD _{IN} | Duty Cycle Distortion tolerance SAC_CLK | 30 | | 70 | % |
| $f_{\sf max}$ | Clock frequency for high speed interface DCLK | 20 | 76.2 | 80 | MHz |
| DCD _{IN} | Duty Cycle Distortion tolerance DCLK | 30 | | 70 | % |
| TEMPERATURE | DIODE | ' | | | |
| I _{TEMP_DIODE} | Max current source into temperature diode | | | 120 | uA |
| ENVIRONMENTA | AL . | | | | |
| T _{ARRAY} | Operating DMD array temperature ⁽³⁾ | - 40 | | 105 | °C |
| ILL _{UV} | Illumination, wavelength < 395 nm ⁽²⁾ | | | 2 | mW/cm ² |
| ILL _{OVERFILL} | Illumination overfill maximum heat load in area shown in Illumination Overfill Diagram | | | 40 | mW/mm |
| | _ | | | | |

- (1) Recommended Operating Conditions are applicable after the DMD is installed in the final product.
- (2) The maximum operation conditions for operating temperature and UV illumination shall not be implemented simultaneously.
- 3) Operating profile information for device micromirror landed duty-cycle and temperature may be provided if requested.

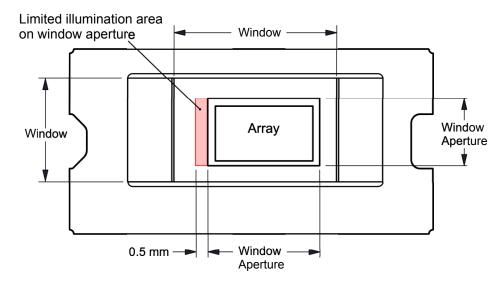


图 7-1. Illumination Overfill Diagram

7.5 Thermal Information

| | | DLP2021-Q1 | |
|--------------------|---------------------------------------|------------|------|
| | THERMAL METRIC | FQU | UNIT |
| | | 64 PINS | |
| Thermal resistance | Active area-to-test point 1 (TP1) (1) | 5 | °C/W |

(1) The DMD is designed to conduct absorbed and dissipated heat to the back of the package. The cooling system must be capable of maintaining the package within the temperature range specified in the Recommended Operating Conditions. The total heat load on the DMD is largely driven by the incident light absorbed by the active area, although other contributions include light energy absorbed by the window aperture and electrical power dissipation of the array. Optical systems should be designed to minimize the light energy

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falling outside the window clear aperture since any additional thermal load in this area can significantly degrade the reliability of the device.

7.6 Electrical Characteristics

Over operating free-air temperature range (unless otherwise noted) (1)

| | PARAMETER | TEST CONDITIONS | MIN | TYP MAX | UNIT |
|---------------------|---|---------------------------------------|-----------------------|-----------------------|------|
| CURRENT | • | | | | |
| I _{DD} | Supply current: V _{DD} | V _{DD} = 1.95 V | | 30 | mA |
| I _{OFFSET} | Supply current: V _{OFFSET} | V _{OFFSET} = 8.75 V | | 15 | mA |
| I _{BIAS} | Supply current: V _{BIAS} | V _{BIAS} = 16.5 V | | 2.3 | mA |
| I _{RESET} | Supply current: V _{RESET} | V _{RESET} = - 10.5 V | | 3.3 | mA |
| POWER | | | | | |
| P _{DD} | Supply power dissipation: V _{DD} | V _{DD} = 1.95 V | | 60 | mW |
| P _{OFFSET} | Supply power dissipation: V _{OFFSET} | V _{OFFSET} = 8.75 V | | 132 | mW |
| P _{BIAS} | Supply power dissipation: V _{BIAS} | V _{BIAS} = 16.5 V | | 38 | mW |
| P _{RESET} | Supply power dissipation: V _{RESET} | V _{RESET} = - 10.5 V | | 30 | mW |
| P _{TOTAL} | Supply power dissipation: Total | | | 260 | mW |
| LVCMOS E | Buffers | · | | | |
| V _{OH} | High level output voltage | I _{OH} = -2 mA | 0.8 × V _{DD} | | V |
| V _{OL} | Low level output voltage | I _{OH} = 2 mA | | 0.2 × V _{DD} | V |
| I _{IL} | Low level input current ⁽²⁾ | VDD = 1.95 V; V _I = 0 V | - 100 | | nA |
| I _{IH} | High level output current ⁽²⁾ | VDD = 1.95 V; V _I = 1.95 V | | 135 | uA |
| I _{IL2} | Low level input current ⁽³⁾ | V _{DD} = 0.0 V | - 5 | | uA |
| I _{IH2} | High level output current ⁽³⁾ | V _{DD} = 1.95 V | | 785 | uA |
| CAPACITA | ANCE | 1 | | | |
| C _{IN} | Input capacitance | f = 1 MHz | | 10 | pF |
| C _{OUT} | Output capacitance | f = 1 MHz | | 15 | pF |
| C _{TEMP} | Temperature sense diode capacitance | f = 1 MHz | | 25 | pF |

- (1) Device electrical characteristics are over Recommended Operating Conditions unless otherwise noted.
- (2) Specification is for LVCMOS input pins which do not have pull up or pull down resistors.
- (3) Specification is for LVCMOS input pins which do have pull down resistors.

7.7 Timing Requirements

Device electrical characteristics are over Recommended Operating Conditions unless otherwise noted

| | | MIN | NOM | MAX | UNIT |
|------------------|--|-----|-----|-----|------|
| DMD MIRROR AND S | RAM CONTROL LOGIC SIGNALS | | | | |
| t _{su} | Setup time SAC_BUS low before SAC_CLK † | 1 | | | ns |
| t _h | Hold time SAC_BUS low after SAC_CLK † | 1 | | | ns |
| t _{su} | Setup time DAD_BUS high before SAC_CLK ↑ | 1 | | | ns |
| t _h | Hold time DAD_BUS high after SAC_CLK ↑ | 1 | | | ns |
| DMD DATA PATH AN | D LOGIC CONTROL SIGNALS | | | | |
| t _{su} | Setup time DATA(9:0) before DCLK ↑ or DCLK ↓ | 1.0 | | | ns |
| t _h | Hold time DATA(9:0) after DCLK ↑ or DCLK ↓ | 1.0 | | | ns |
| t _{su} | Setup time SCTRL before DCLK ↑ or DCLK ↓ | 1.0 | | | ns |
| t _h | Hold time SCTRL after DCLK ↑ or DCLK ↓ | 1.0 | | | ns |
| t _{su} | Setup time TRC before DCLK ↑ or DCLK ↓ | 1.0 | | | ns |
| t _h | Hold time TRC after DCLK ↑ or DCLK ↓ | 1.0 | | | ns |

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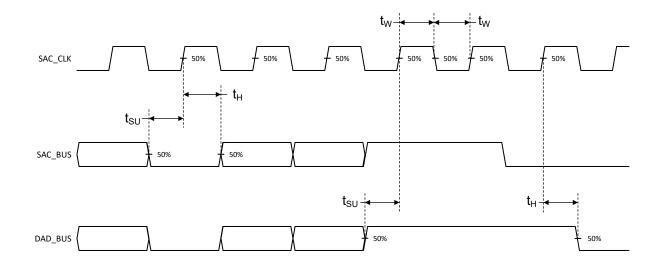
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7.7 Timing Requirements (continued)

Device electrical characteristics are over Recommended Operating Conditions unless otherwise noted

| | | MIN | NOM | MAX | UNIT |
|-----------------|--|-----|-----|-----|------|
| t _{su} | Setup time LOADB low before DCLK ↑ or DCLK ↓ | 1.0 | | | ns |
| t _h | Hold time LOADB low after DCLK ↑ or DCLK ↓ | 1.0 | | | ns |
| t _{su} | Setup time RESET_STROBE high before DCLK † or DCLK ↓ | 1.5 | | | ns |
| t _h | Hold time RESET_STROBE high after DCLK ↑ or DCLK ↓ | 1.5 | | | ns |
| t _w | Pulse width 50% to 50% reference points: DCLK high or low | 5 | | | ns |
| t _w | pulse width 50% to 50% reference points: LOADB low | 7 | | | ns |
| t _w | pulse width 50% to 50% reference points: RESET_STROBE high | 7 | | | ns |
| t _r | Rise time 20% to 80% reference points: DCLK, DATA, SCTRL, TRC, LOADB,SAC_CLK | | | 2.5 | ns |
| t _f | Fall time 80% to 20% reference points: DCLK, DATA, SCTRL, TRC, LOADB,SAC_CLK | | | 2.5 | ns |



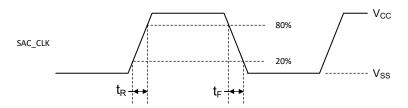
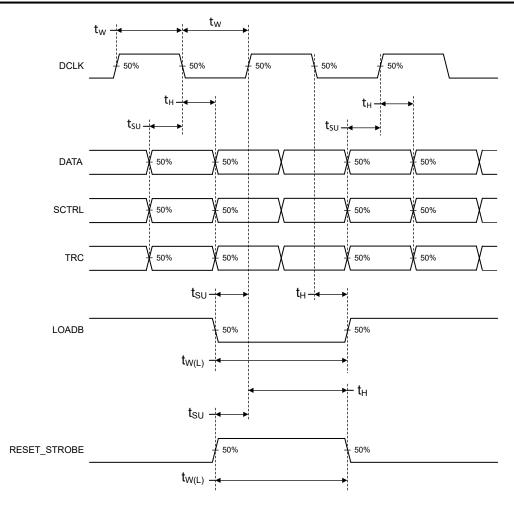


图 7-2. DMD Mirror and SRAM Control Logic Timing Requirements

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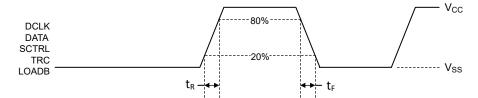


图 7-3. DMD Data Path and Control Logic Timing Requirements

7.8 System Mounting Interface Loads

| | MIN | NOM | MAX | UNIT | |
|---------------------------|---|-----|-----|------|----|
| Thermal Interface Area | Area Uniformly distributed within the Thermal Interface Area shown ii 图 7-4 | | | 70 | N |
| Electrical Interface Area | Uniformly distributed within the Electrical Interface Area shown in ⊠ 7-4 | | | 100 | IV |



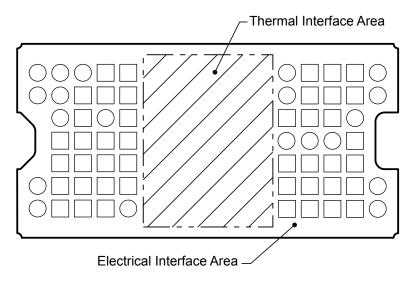


图 7-4. System Interface Loads

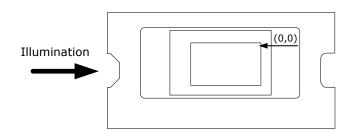
7.9 Micromirror Array Physical Characteristics

| | PARAMETER | VALUE | UNIT | |
|---|--|--------------------------------|-------|-------------------|
| М | Number of active columns ⁽¹⁾ | | 416 | micromirrors |
| N | Number of active rows ⁽¹⁾ | | 468 | micromirrors |
| ε | Micromirror Pitch (diagonal) ⁽²⁾ | | 7.6 | μm |
| Р | Micromirror Pitch (horizontal and vertical) ⁽²⁾ | | 10.8 | μm |
| | Micromirror active array width | (P × M) + (P / 2) | 4.498 | mm |
| | Micromirror active array height | (P x N) / 2 + (P / 2) | 2.533 | mm |
| | Micromirror active border | Pond of micromirrors (POM) (3) | 10 | micromirrors/side |

- (1) See Array Physical Characteristics.
- (2) See Pixel Pitch.
- (3) The structure and qualities of the border around the active array includes a band of partially functional micromirrors called the POM. These micromirrors are structurally and/or electrically prevented from tilting toward the bright or ON state, but still require an electrical bias to tilt toward OFF.

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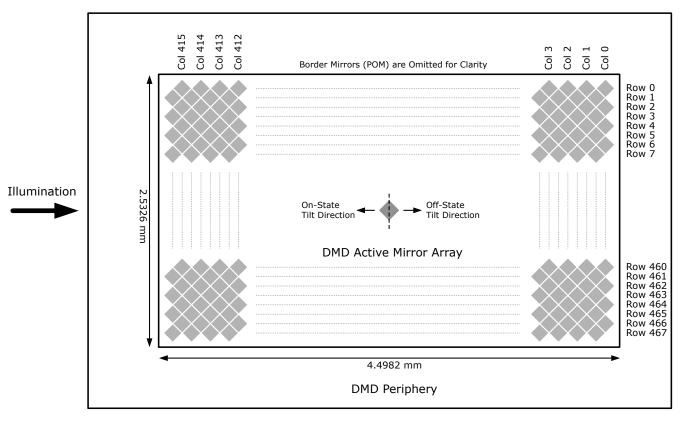


图 7-5. Micromirror Array Physical Characteristics

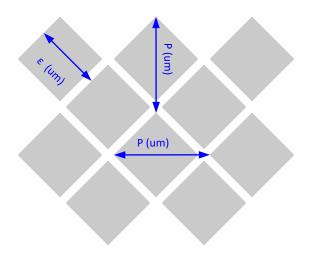


图 7-6. Mirror (Pixel) Pitch



7.10 Micromirror Array Optical Characteristics

| PARAMETER | TEST CONDITIONS | MIN | NOM | MAX | UNIT |
|-------------------------------|---------------------------------|-----|-----|-----|--------|
| Micromirror tilt angle | DMD landed state ⁽¹⁾ | 11 | 12 | 13 | degree |
| DMD efficiency ⁽²⁾ | 420 nm - 700 nm | | 66% | | |

- (1) Measured relative to the plane formed by the overall micromirror array at 25°C
- 2) DMD efficiency is measured photopically under the following conditions: 24° illumination angle, F/2.4 illumination and collection apertures, uniform source spectrum (halogen), uniform pupil illumination, the optical system is telecentric at the DMD, and the efficiency numbers are measured with 100% electronic micromirror landed duty-cycle and do not include system optical efficiency or overfill loss. This number is measured under conditions described above and deviations from these specified conditions could result in a different efficiency value in a different optical system. The factors that can influence the DMD efficiency related to system application include: light source spectral distribution and diffraction efficiency at those wavelengths (especially with discrete light sources such as LEDs or lasers), and illumination and collection apertures (F/#) and diffraction efficiency. DLPA083A describes the interaction of these system factors, as well as the DMD efficiency factors that are not system dependent.

7.11 Window Characteristics

| PARAMETER | | MIN | NOM | MAX | UNIT |
|--|---|-----------------|--------|---------|------|
| Window material designation | С | orning Eagle XG | | | |
| Window refractive index at wavelength 546.1 nm | | | 1.5119 | | |
| Window aperture (1) | | | | See (1) | |

1) See the mechanical package ICD for details regarding the size and location of the window aperture.

7.12 Chipset Component Usage Specification

The DLP2021-Q1 DMD is a component of a Texas Instruments DLP® chipset including a DLP products controller. Reliable function and operation of the DMD requires that it be used in conjunction with a DLP products controller.

备注

TI assumes no responsibility for image quality artifacts or DMD failures caused by optical system operating conditions exceeding limits described previously.

Product Folder Links: DLP2021-Q1

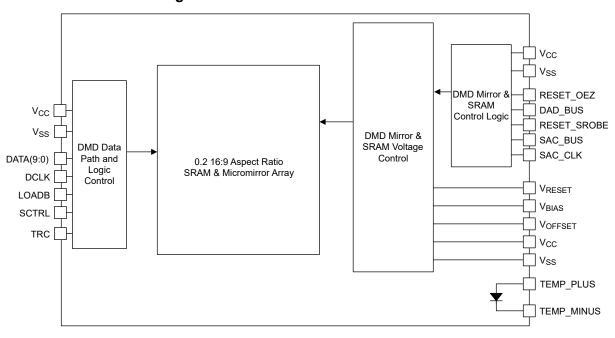


8 Detailed Description

8.1 Overview

The DLP2021-Q1 DMD has a resolution of 416×468 mirrors configured in a diamond format that results in an aspect ratio of 16:9 which creates an effective resolution of 588×330 square pixels. By configuring the pixels in a diamond format, the illumination input to the DMD enters from the side allowing for smaller mechanical packaging of the optical system.

8.2 Functional Block Diagram





8.3 Feature Description

To ensure reliable operation, the DLP2021-Q1 DMD must be used with a DLP products controller.

8.3.1 Micromirror Array

The DLP2021-Q1 DMD consists of a two-dimensional array of 1-bit CMOS memory cells that determine the state of the each of the 416 \times 468 micromirrors in the array. Refer to \dagger 7.9 section for a calculation of how the 416 \times 468 micromirror array represents a 16:9 dimensional aspect ratio to the user. Each micromirror is either ON (tilted +12°) or OFF (tilted - 12°). Combined with appropriate projection optical system the DMD can be used to create sharp, colorful, and vivid digital images.

8.3.2 Double Data Rate (DDR) Interface

Each DMD micromirror and its associated SRAM memory cell is loaded with data from the DLP controller via the DDR interface (DATA(9:0), DCLK, LOADB, SCRTL, and TRC). These signals are low voltage CMOS nominally operating at 1.8-V level to reduce power and switching noise. This high speed data input to the DMD allows for a maximum update rate of the entire micromirror array to be nearly 5 kHz, enabling the creation of seamless digital images using Pulse Width Modulation (PWM).

8.3.3 Micromirror Switching Control

Once data is loaded onto the DMD, the mirrors switch position (+12° or - 12°) based on the timing signal sent to the DMD Mirror and SRAM control logic. The DMD mirrors will be switched from OFF to ON or ON to OFF, or stay in the same position based on control signals DAD_BUS, RESET_STROBE, SAC_BUS, and SAC_CLK, which are coordinated with the data loading by the DLP controller. In general, the DLP controller loads the DMD SRAM memory cells over the DDR interface, and then commands to the micromirrors to switch position.

At power down, the DMD Mirrors are commanded by the DLP controller to move to a near flat (0°) position as shown in \ddagger 10. The flat state position of the DMD mirrors are referred to as the "Parked" state. To maintain long-term DMD reliability, the DMD must be properly "Parked" prior to every power down of the DMD power supplies.

8.3.4 DMD Voltage Supplies

The micromirrors switching requires unique voltage levels to control the mechanical switching. These voltages levels are nominally 16 V, 8.5 V, and $^-$ 10 V (V_{BIAS}, V_{OFFSET}, and V_{RESET}). The specification values for V_{BIAS}, V_{OFFSET}, and V_{RESET} are shown in ‡ 7.4.

8.3.5 Logic Reset

Reset of the DMD is required and controlled by the DLP products controller.

8.3.6 Temperature Sensing Diode

The DMD includes a temperature sensing diode designed to be used with the TMP411-Q1 or equivalent temperature monitoring device.

8-1 shows the typical connection between the DLP products controller, TMP411-Q1, and the DLP2021-Q1 DMD. The signals to the temperature sense diode are sensitive to system noise, and care should be taken in the routing and implementation of this circuit. See the TMP411-Q1 data sheet for detailed PCB layout recommendations.

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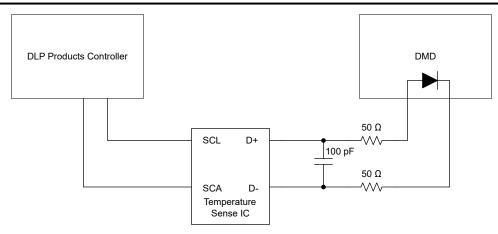


图 8-1. Temperature Sense Diode Typical Circuit Configuration

It is recommended that the host controller manage parking of the DMD based on the allowable temperature specifications and temperature measurements.

8.3.6.1 Temperature Sense Diode Theory

A temperature sensing diode is based on the fundamental current and temperature characteristics of a transistor. The diode is formed by connecting the transistor base to the collector. Two different known currents flow through the diode and the resulting diode voltage is measured in each case. The difference in the base-emitter voltages is proportional to the absolute temperature of the transistor.

Refer to the *TMP411-Q1 data sheet* for detailed information about temperature diode theory and measurement.

8 8-2 and 8 8-3 illustrate the relationship between the current and voltage through the diode.

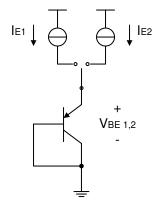


图 8-2. Temperature Measurement Theory

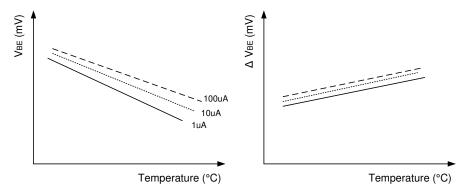


图 8-3. Example of Delta VBE vs Temperature



8.4 System Optical Considerations

Optimizing system optical performance and image performance strongly relates to optical system design parameter trades. Although it is not possible to anticipate every conceivable application, projector image quality and optical performance is contingent on compliance to the optical system operating conditions described in the following sections.

8.4.1 Numerical Aperture and Stray Light Control

The angle defined by the numerical aperture of the illumination and projection optics at the DMD optical area should be the same. This angle should not exceed the nominal device mirror tilt angle unless appropriate apertures are added in the illumination and/or projection pupils to block flat-state and stray light from passing through the projection lens. The mirror tilt angle defines DMD capability to separate the "On" optical path from any other light path, including undesirable flat-state specular reflections from the DMD window, DMD border structures, or other system surfaces near the DMD such as prism or lens surfaces. If the numerical aperture exceeds the mirror tilt angle, or if the projection numerical aperture angle is more than two degrees larger than the illumination numerical aperture angle, contrast ratio can be reduced and objectionable artifacts in the image border and/or active area could occur.

8.4.2 Pupil Match

TI's optical and image quality specifications assume that the exit pupil of the illumination optics is nominally centered within two degrees of the entrance pupil of the projection optics. Misalignment of pupils can create objectionable artifacts in the image border and/or active area, which may require additional system apertures to control, especially if the numerical aperture of the system exceeds the pixel tilt angle.

8.4.3 Illumination Overfill and Alignment

Overfill light illuminating the area outside the active array can create artifacts from the mechanical features and other surfaces that surround the active array. These artifacts may be visible in the projected image. The illumination optical system should be designed to minimize light flux incident outside the active array and on the window aperture. Depending on the particular system's optical architecture and assembly tolerances, this amount of overfill light on the area outside of the active array may still cause artifacts to be visible. Illumination light and overfill can also induce undesirable thermal conditions on the DMD, especially if illumination light impinges directly on the DMD window aperture or near the edge of the DMD window. Refer to † 7.4 for a specification on this maximum allowable heat load due to illumination overfill.

Product Folder Links: DI P2021-Q1



8.5 DMD Image Performance Specification

| PARAMETER | | MIN | NOM | MAX | UNIT |
|---|---------------------------|-----|-----------|-----|----------------|
| Number of non-operational micromirrors ⁽¹⁾ | Adjacent micromirrors | | | 0 | micromirrors |
| Number of non-operational microminors | Non-adjacent micromirrors | | | 10 | THICIOITHITOIS |
| Optical performance | | | See 节 8.4 | | |

(1) A non-operational micromirror is defined as a micromirror that is unable to transition between the on-state and off-state positions.

8.6 Micromirror Array Temperature Calculation

Active array temperature can be computed analytically from measurement points on the outside of the package, the package thermal resistance, the electrical power, and the illumination heat load.

Relationship between array temperature and the reference ceramic temperature (thermocouple location TP1 in 8-4) is provided by the following equations.

$$T_{ARRAY} = T_{CERAMIC} + (Q_{ARRAY} \times R_{ARRAY-TO-CERAMIC})$$
 (1)

$$Q_{ARRAY} = Q_{ELECTRICAL} + Q_{ILLUMINATION}$$
 (2)

where

- T_{ARRAY} = computed DMD array temperature (°C)
- T_{CERAMIC} = measured ceramic temperature (TP1 location in 图 8-4) (°C)
- R_{ARRAY-TO-CERAMIC} = DMD package thermal resistance from array to TP1 (°C/watt) (see 节 7.5)
- Q_{ARRAY} = total power, electrical plus absorbed, on the DMD array (watts)
- Q_{ELECTRICAL} = nominal electrical power dissipation by the DMD (watts)
- $Q_{ILLUMINATION} = (C_{L2W} \times S_L)$
- C_{L2W} = conversion constant for screen lumens to power on the DMD (watts/lumen)
- S_I = measured screen lumens (Im)

Electrical power dissipation of the DMD is variable and depends on the voltages, data rates, and operating frequencies.

Absorbed power from the illumination source is variable and depends on the operating state of the mirrors and the intensity of the light source.

Equations shown previous are valid for a 1-Chip DMD system with total projection efficiency from DMD to the screen of 87%.

The constant C_{L2W} is based on the DMD array characteristics. It assumes a spectral efficiency of 300 lumens/ watt for the projected light and illumination distribution of 83.7% on the active array, and 16.3% on the array border.

Sample calculation:

- $S_L = 50 \text{ Im}$
- $C_{1.2W} = 0.00293 \text{ W/Im}$
- Q_{ELECTRICAL} = 0.105 W
- R_{ARRAY-TO-CERAMIC} = 5°C/W
- T_{CERAMIC} = 55°C

$$Q_{ARRAY} = 0.105 \text{ W} + (0.00293 \times 50 \text{ lm}) = 0.252 \text{ W}$$
 (3)

$$T_{ARRAY} = 55^{\circ}C + (0.252 \text{ W} \times 5^{\circ}C/\text{W}) = 56.26$$
 (4)



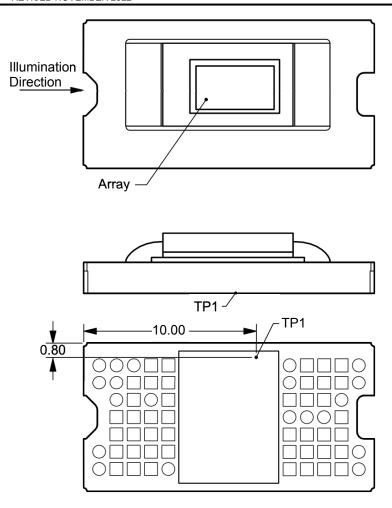


图 8-4. Thermocouple Location

8.7 Micromirror Landed-On/Landed-Off Duty Cycle

The micromirror landed-on/landed-off duty cycle (landed duty cycle) denotes the amount of time (as a percentage) that an individual micromirror is landed in the ON state versus the amount of time the same micromirror is landed in the OFF state.

As an example, assuming a fully-saturated white pixel, a landed duty cycle of 90/10 indicates that the referenced pixel is in the ON state 90% of the time (and in the OFF state 10% of the time), whereas 10/90 would indicate that the pixel is in the OFF state 90% of the time. Likewise, 50/50 indicates that the pixel is ON 50% of the time and OFF 50% of the time.

Note that when assessing landed duty cycle, the time spent switching from one state (ON or OFF) to the other state (OFF or ON) is considered negligible and is thus ignored.

Since a micromirror can only be landed in one state or the other (ON or OFF), the two numbers (percentages) always add to 100.

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9 Application and Implementation

备注

以下应用部分中的信息不属于 TI 器件规格的范围, TI 不担保其准确性和完整性。TI 的客户应负责确定器件是否适用于其应用。客户应验证并测试其设计,以确保系统功能。

9.1 Application Information

The DLP2021-Q1 DMD was designed to be used in automotive applications such as dynamic ground projection. The information shown in this section describes the dynamic ground projection application.

9.2 Typical Application

The DLP2021-Q1 DMD combined with a DLP products controller are the primary devices that make up the reference design for a dynamic ground projection system as shown in the block diagram

9-1.

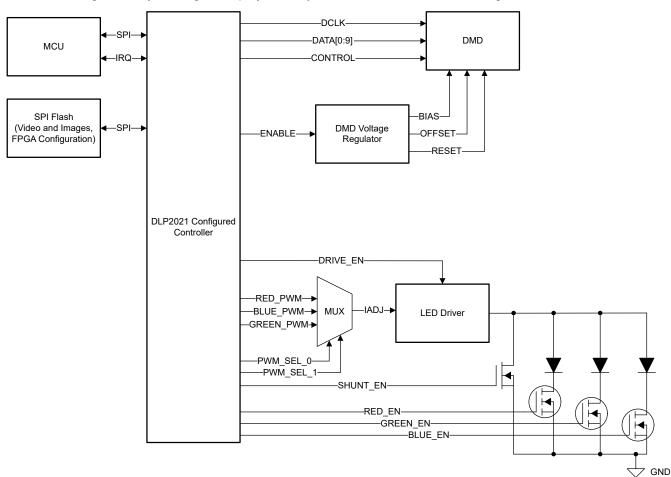


图 9-1. Dynamic Ground Projection System Block Diagram

In this architecture, video content is compressed and stored in external flash memory. Low speed SPI commands are sent from a microcontroller or other processor to the DLP products controller to indicate what video content to read from external memory. Storing the video content in memory removes the need for a high speed video interface to the module which improves compatibility with typical vehicle infrastructures. It also decreases overall system size and cost by removing graphics generation and interfaces. The controller decompresses each bit plane of the video data (416 \times 468 resolution) and displays them on the DMD in rapid succession to create the full video image. Due to the diamond format of the DMD pixels, the output image has an



effective resolution of 588×330 . The controller synchronizes the DMD bit plane data with the RGB enable timing for the LED color controller and driver circuit.

The controller may connect to a TMP411-Q1 to measure the DLP2021-Q1 temperature using the built-in temperature sensing diode.

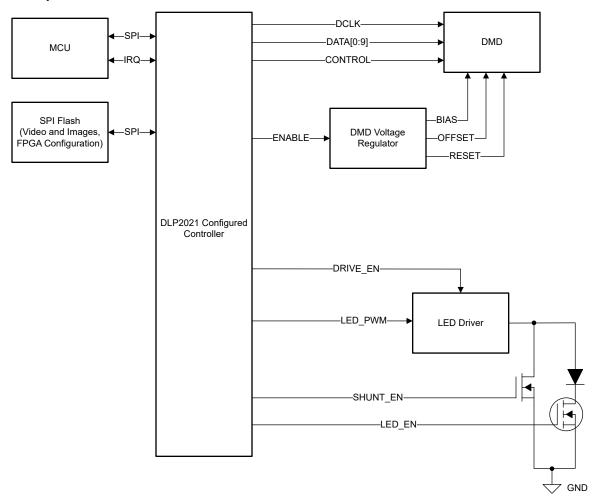


图 9-2. Dynamic Ground Projection System Block Diagram - Single Color

9.3 Application Mission Profile Consideration

Each application is anticipated to have different mission profiles, or number of operating hours at different temperatures. To assist in evaluation, the automotive DMD reliability lifetime estimates Application Report may be provided. See the TI Application team for more information.

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10 Power Supply Recommendations

10.1 Power Supply Sequencing Requirements

V_{BIAS}, V_{CC}, V_{OFFSET}, V_{RESET}, V_{SS} are required to operate the DMD.

CAUTION

- For reliable operation of the DMD, the following power supply sequencing requirements must be followed. Failure to adhere to the prescribed power up and power down procedures may affect device reliability.
- The V_{CC}, V_{OFFSET}, V_{BIAS}, and V_{RESET} power supplies have to be coordinated during power up and power down operations. Failure to meet any of the following requirements will result in a significant reduction in the DMD's reliability and lifetime. Refer to

 10-1. V_{SS} must also be connected.

DMD Power Supply Power Up Procedure:

- During power up, V_{CC} must always start and settle before V_{OFFSET}, V_{BIAS} and V_{RESET} voltages are applied to the DMD.
- During power up, V_{BIAS} does not have to start after V_{OFFSET}. However, it is a strict requirement that the delta between V_{BIAS} and V_{OFFSET} must be within ±8.75 V (refer to Note 1 for 图 10-1).
- During power up, the DMD's LVCMOS input pins shall not be driven high until after V_{CC} has settled at operating voltage.
- During power up, there is no requirement for the relative timing of V_{RESET} with respect to V_{OFFSET} and V_{BIAS}.
- Power supply slew rates during power up are flexible, provided that the transient voltage levels follow the requirements listed previously in 节 7.4 and in 图 10-1.

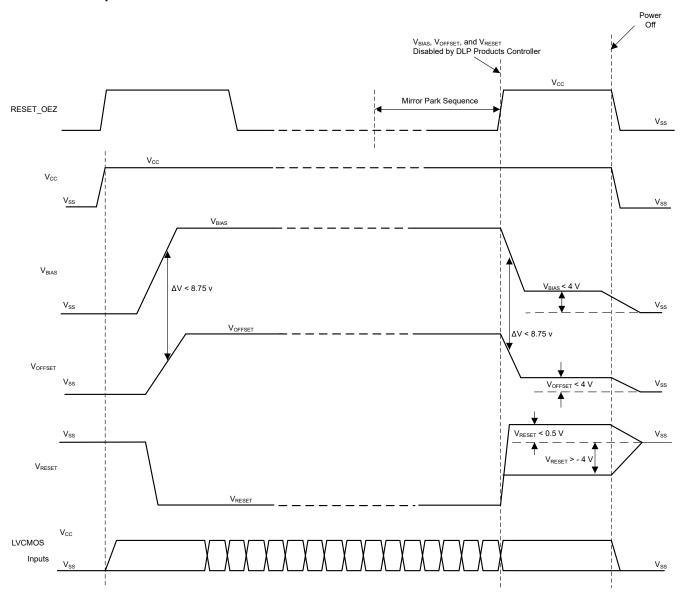
DMD Power Supply Power Down Procedure

- V_{CC} must be supplied until after V_{BIAS}, V_{RESET}, and V_{OFFSET} are discharged to within 4 V of ground.
- During power down it is not mandatory to stop driving V_{BIAS} prior to V_{OFFSET}, but it is a strict requirement that the delta between V_{BIAS} and V_{OFFSET} must be within ±8.75 V (refer to Note 1 for

 10-1).
- During power down, the DMD's LVCMOS input pins must be less than V_{CC} + 0.3 V.
- During power down, there is no requirement for the relative timing of V_{RESET} with respect to V_{OFFSET} and V_{RIAS}.
- Power supply slew rates during power down are flexible, provided that the transient voltage levels follow the requirements listed previously in 节 7.4 and in 图 10-1.



10.1.1 Power Up and Power Down



A. ± 8.75 -V delta, Δ V, shall be considered the max operating delta between V_{BIAS} and V_{OFFSET} . Customers may find that the most reliable way to ensure this is to power V_{OFFSET} prior to V_{BIAS} during power up and to remove V_{BIAS} prior to V_{OFFSET} during power down.

图 10-1. Power Supply Sequencing Requirements (Power Up and Power Down)

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11 Layout

11.1 Layout Guidelines

For specific DMD PCB guidelines, use the following:

- V_{CC} should have at least 1 × 2.2-μF and 4 × 0.1-μF capacitors evenly distributed among the 6 V_{CC} pins.
- A 0.1-μF, X7R rated capacitor should be placed near every pin for V_{BIAS}, V_{RSET}, and V_{OFF}.

11.2 Temperature Diode Pins

The DMD has an internal diode (PN junction) that is intended to be used with an external TI TMP411-Q1 or equivalent temperature sensing IC. PCB traces from the DMD's temperature diode pins to the TMP411-Q1 are sensitive to noise. See the *TMP411-Q1 data sheet* for specific routing recommendations.

Avoid routing the temperature diodes signals near other traces to reduce coupling of noise onto these signals.



12 Device and Documentation Support

12.1 Device Support

12.1.1 Device Nomenclature

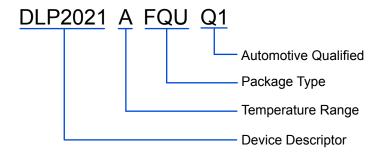


图 12-1. Part Number Description

12.1.2 Device Markings

The device marking is shown in 🖺 12-2. The marking will include both human-readable information and a 2-dimensional matrix code.

The human-readable information is described in

12-2. The 2-dimensional matrix code is an alpha-numeric character string that contains the DMD part number and lot trace code.

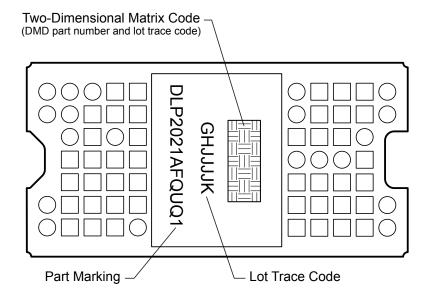


图 12-2. DMD Marking

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12.2 Documentation Support

12.2.1 Related Documentation

For related documentation see the following:

- Texas Instruments, TMP411-Q1 ±1°C Remote and Local Temperature Sensor With N-Factor and Series Resistance Correction data sheet
- Texas Instruments, DMD Optical Efficiency for Visible Wavelengths application report

12.3 接收文档更新通知

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12.4 支持资源

TI E2E™ 支持论坛是工程师的重要参考资料,可直接从专家获得快速、经过验证的解答和设计帮助。搜索现有解答或提出自己的问题可获得所需的快速设计帮助。

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12.6 Electrostatic Discharge Caution



This integrated circuit can be damaged by ESD. Texas Instruments recommends that all integrated circuits be handled with appropriate precautions. Failure to observe proper handling and installation procedures can cause damage.

ESD damage can range from subtle performance degradation to complete device failure. Precision integrated circuits may be more susceptible to damage because very small parametric changes could cause the device not to meet its published specifications.

12.7 Device Handling

The DMD is an optical device so precautions should be taken to avoid damaging the glass window. Please see the DMD Handling application note for instructions on how to properly handle the DMD.

12.8 术语表

TI术语表本术语表列出并解释了术语、首字母缩略词和定义。

13 Mechanical, Packaging, and Orderable Information

The following pages include mechanical, packaging, and orderable information. This information is the most current data available for the designated devices. This data is subject to change without notice and revision of this document. For browser-based versions of this data sheet, refer to the left-hand navigation.



13.1 Package Option Addendum

Packaging Information

| Orderable Device | Status | Package Type | Package Drawing | Pins | Package Qty | Eco Plan | Lead/Ball Finish | MSL Peak Temp | Op Temp (°C) | Device Marking |
|------------------|---------|-----------------|-----------------|------|-------------|----------|---------------------|------------------|--------------|-------------------|
| XDLP2021AFQUQ1 | PREVIEW | CLGA | FQU | 54 | 126 | Green | Call TI | N/A for Pkg Type | -40 to 105 | |

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